

Notice of References Cited

Application/Control No.

09/879,428

Applicant(s)/Patent Under
Reexamination
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Examiner

Thomas R Artman

Art Unit

2882

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	C	US-4,413,908	11-1983	Abrams et al.	356/452
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FOREIGN PATENT DOCUMENTS

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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
*	U	Hines, B. et al., "Sub-nanometer laser metrology - some techniques and models," Jet Propulsion Laboratory, California Institute of Technology, pp.1195-1204
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.